

CLAIMS

What is claimed is:

1. A porous tower diffuser assembly for use in a front opening wafer container, the diffuser assembly comprising:

an inlet fitting with a base portion, a unitary offset portion, and a unitary upwardly facing nipple, the inlet fitting configured to be seated in an aperture in a bottom wall of the front opening container;

a porous tower configured as a sintered polymer tubular portion including a lower portion, the lower portion having a larger diameter portion and engaged on the upwardly facing nipple;

the porous tower portion having at least two different portions of different resistances to radial outflow of purge gases.

2. The porous tower diffuser assembly of claim 1 wherein the upwardly facing nipple has a plurality of barbs or a thread sized for an interference fit with the porous tower.

3. The porous tower diffuser assembly of claim 2 comprising a radial aperture in the nipple.

4. The porous tower diffuser assembly of claim 1, in combination with a front opening wafer container and a second identical porous tower diffuser assembly.

5. A front opening wafer container comprising a container portion with a front opening and a door to sealingly close the front opening, the container portion having a bottom wall, the front opening wafer container further comprising:

an inlet fitting with a base portion, a unitary offset portion, and a unitary upwardly facing nipple, the fitting seated at an aperture in the bottom wall;

a porous tower configured as a sintered polymer tubular portion including a lower portion having a larger diameter portion, the lower portion engaged on the upwardly facing nipple.

6. The front opening wafer container of claim 5 wherein the nipple has one of barbs or a thread, a radial aperture, and wherein an annularly extending space is defined between the nipple and the porous tower at the radial aperture.

7. The front opening wafer container of claim 5 further comprising a means for increasing purge towards the flared lower portion compared to a portion distal from the flared lower portion.

8. The front opening wafer container of claim 5 further comprising another inlet fitting with a base portion, a unitary offset portion, and a unitary upwardly facing nipple, the fitting seated at another aperture in the bottom wall;

another porous tower configured as a sintered polymer tubular portion and a flared lower portion, the flared lower portion engaged on the upwardly facing nipple.